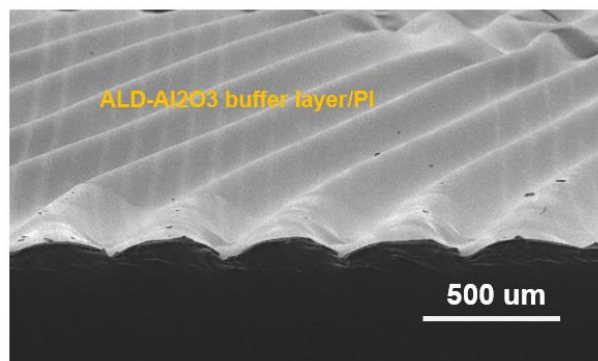


Supplementary

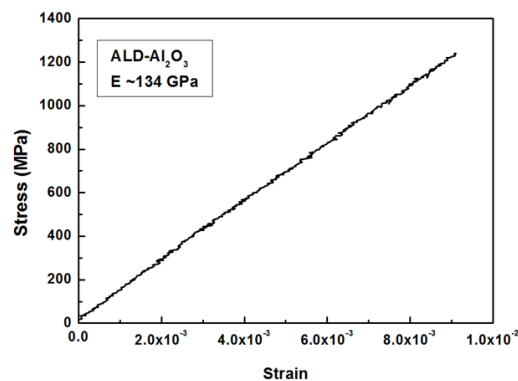
ALD- Al_2O_3 buffer layer, a key component for realizing stretchable thin film transistor arrays

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- 1) An SEM image showing ALD- Al_2O_3 buffer layer formed on wavy PI support



- 2) Measured mechanical property on ALD- Al_2O_3 buffer layer



Ref) Kim, JH., Nizami, A., Hwangbo, Y. et al. Tensile testing of ultra-thin films on water surface. Nat Commun 4, 2520 (2013).

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